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ABSTRACT

SUBSTRATE TRANSFER ROBOT AND VACUUM PROCESSING
APPARATUS PROVIDED WITH THE SAME

10 Provided is substrate transfer robot which can surely eliminate adhesion,
shifting, dropping and the like of substrate at the time of transferring the
substrate. A vacuum processing apparatus provided with such substrate
transfer robot is also provided. The substrate transfer robot is provided with a
substrate receiving section for placing the substrate; a plurality of substrate
15 slip preventing members, which are arranged on the upper surface of the
substrate receiving section at intervals and are composed of an elastic
material; and an extendable/retractable arm section whereupon the substrate
receiving section is arranged at the leading end. On the upper end surface of
the substrate slip preventing member, a protruding section is arranged. The
20 vacuum processing apparatus is configured as a multi-chamber processing
apparatus provided with the substrate transfer robot.

Fig. 1